



**IECON 2012 – The 38<sup>th</sup> Annual Conference of the IEEE  
Industrial Electronics Society**  
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**Special Session on**

**“MEMS, Microsensors and Microactuators”**

**organized by**

Ridha Ben Mrad ([rbenmrad@mie.utoronto.ca](mailto:rbenmrad@mie.utoronto.ca))  
Stefan Gassmann ([stefan.gassmann@uni-rostock.de](mailto:stefan.gassmann@uni-rostock.de))  
Carmen Aracil ([caracil@gte.esi.us.es](mailto:caracil@gte.esi.us.es))

**Call for Papers**

Microelectromechanical Systems (MEMS) is a multidisciplinary research area that is rapidly growing. MEMS are an enabling technology in many applications and are widely used in a number of industrial sectors including biological, medical, automotive, communications, and energy. The rapid developments in microfabrication technologies, microsensors, microactuators and packaging and integration methods open new possibilities in industrial applications of MEMS devices.

The aim of this special session is to provide an opportunity to share best practices in the design, fabrication, testing, packaging and integration of microdevices. It will generate networking opportunities between researchers who have interests in MEMS technologies.

Topics of interest include, but are not limited to:

- Micro sensors and actuators for industry
- MEMS applications in various industrial sectors including power, automation, automotive, fluidic, and biomedical areas
- Modelling and simulation of MEMS
- Integration of MEMS and NEMS
- Optical and RF MEMS
- Microfabrication